

SUPPLEMENTARY INFORMATION

Epitaxial growth of cobalt oxide thin films on sapphire substrates using atmospheric pressure mist chemical vapor deposition

Hou-Guang Chen *, Huei-Sen Wang *, Sheng-Rui Jian, Tung-Lun Yeh, and Jing-Yi Feng

Department of Materials Science and Engineering, I-Shou University, Kaohsiung City 84001, Taiwan;

*Correspondence: houguang@isu.edu.tw; huei@isu.edu.tw

The carbon 1s core level emission of CoO films, which was contributed from the surface carbon contamination layer, can be completely removed after argon-ion sputtering for 30 sec, as shown in Figure S1.

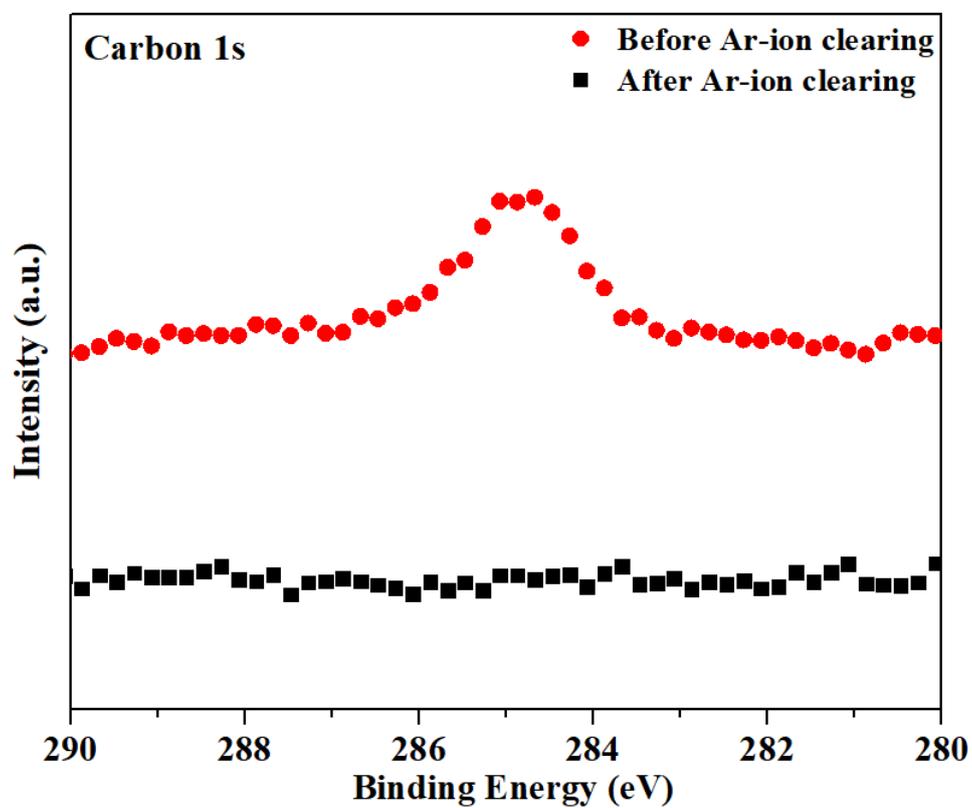


Figure S1. Core-level photoemission spectra of carbon 1s of CoO film before and after argon-ion clearing.